

**Supporting information for  
Ag-Thiolate Interactions to Enable an Ultrasensitive and Stretchable MXene  
Strain Sensor with High Temporospacial Resolution**

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**This PDF file includes:**

Supplementary Note 1 and 2

Supplementary Fig. 1 to 25

Supplementary Table 1

Supplementary Movie 1

Supplementary References

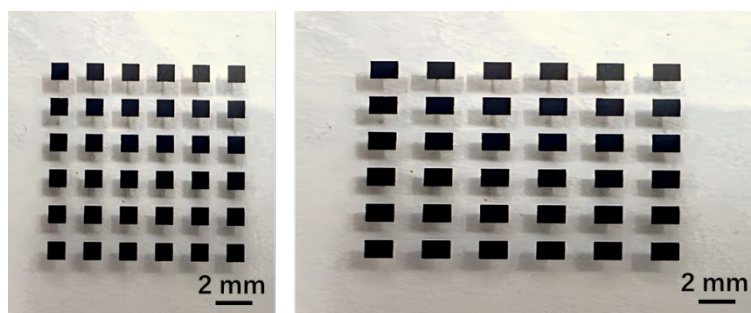
**Supplementary Note 1:**

Figure S5 plots the relative change in resistance of the S-M/A<sub>1</sub> strain sensor with various thicknesses (T) of 2.4, 1.4, and 0.7 μm as a function of applied strain. Obviously, the stretchability of the S-M/A<sub>1</sub> strain sensor increases with the device thickness decreases from thickness of 2.4 to 1.4 μm. The highest GF for the rigid S-M/A<sub>1</sub> strain sensor with device thickness of 2.4 μm was calculated to be 445000 in working strain range of 9-11%. Although the maximum GF drops to 71400 as the device thickness declines to 1.4 from 2.4 μm, the working strain range shows a significant increase from 11% to 45%. This stretchability increase can be attributed to the fact that reducing thickness in the film can render the brittle thin film flexible<sup>1</sup>. With the thickness further decreased to 0.7 μm from 1.4 μm, the stretchability of the S-M/A<sub>1</sub> strain sensor decreased and the GF values increased. This phenomenon was mainly attributed to easier destruction of electrical junctions between adjacent sensing islands under stretching when the sensing film had a very small thickness<sup>2</sup>.

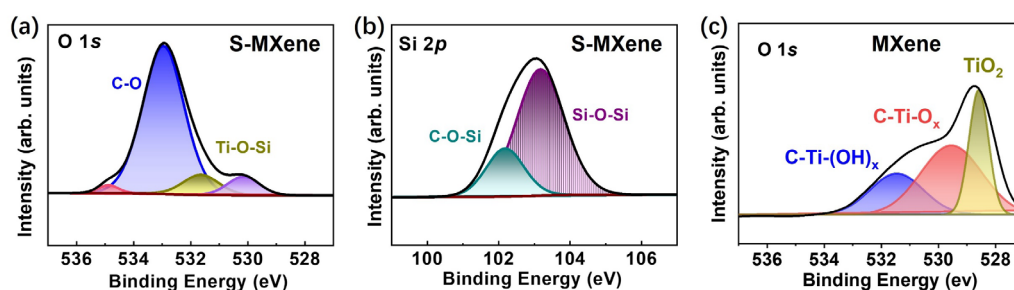
### **Supplementary Note 2:**

We conducted tensile and crack distribution analysis on the model using a standard module of ABAQUS software. The simulation process included the following four steps: (1) Material definition. We utilized the Johnson-Cook damage model and referenced stress-strain curves from previous reports for MXene<sup>3</sup> and AgNW<sup>4</sup>. The fracture condition was set based on the tensile properties of MXene and AgNW. The density, elastic modulus, and tensile strength used in the simulation process for MXene (and S-MXene) was 4.4 g/cm<sup>3</sup>, 80 GPa, and 0.67 GPa<sup>3,5</sup>, and 10.5 g/cm<sup>3</sup>, 86 GPa, and 2 GPa<sup>4,6</sup>, respectively. (2) Contact settings. We then specified frictionless and adhesive contact between AgNW and MXene (or S-MXene). The calculation of Ag-S bonding points was based on the MPTES molecule weight and S-MXene mass, with the adhesion strength defined as 17.74 kcal·mol<sup>-1</sup>. (3) Mesh partitioning. Tetrahedral free mesh partitioning with C3D10 elements for MXene (or S-MXene) and AgNW models was employed. (4) Boundary conditions. We fixed the constraints at one end and the load tensile strain of 10% at the other end.

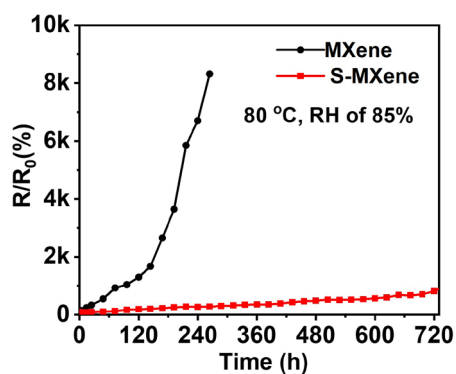
## Supplementary figures and tables



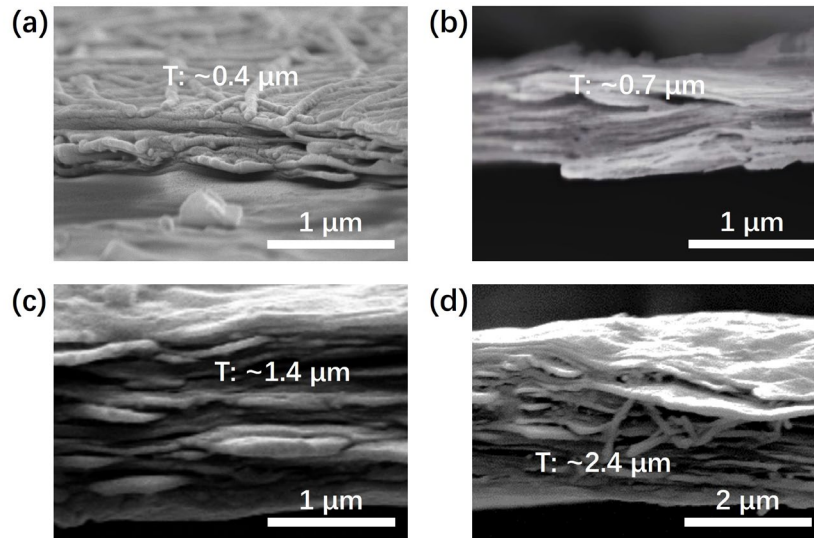
**Supplementary Fig. 1.** S-M/A<sub>1</sub> sensor array in the unstretched state and under 60% strain.



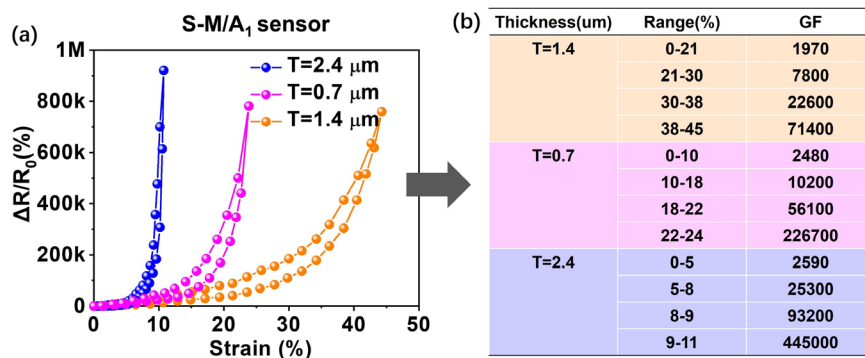
**Supplementary Fig. 2.** XPS spectra of a, b) S-MXene and c) MXene films in the O 1s and Si 2p region.



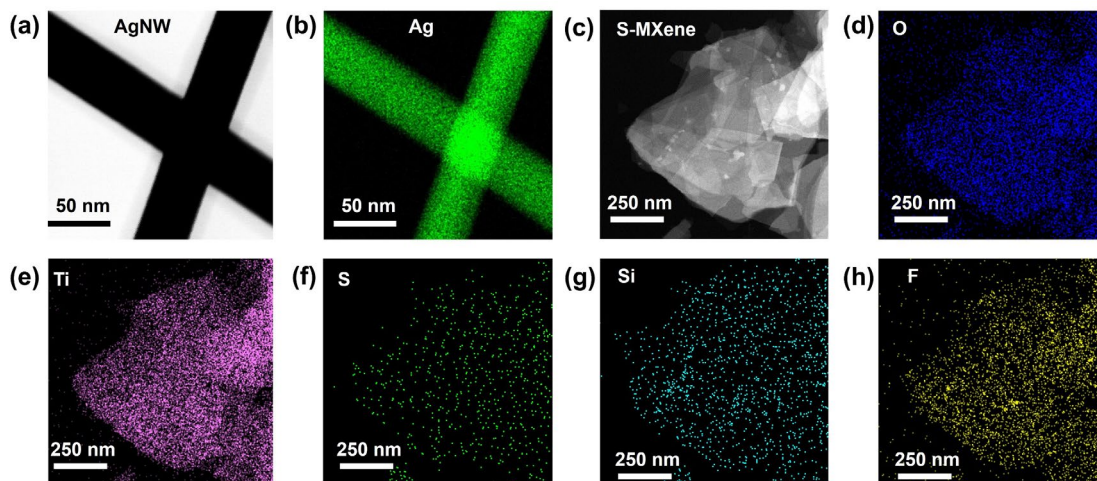
**Supplementary Fig. 3.** Relative resistance changes of MXene and S-MXene after storage in the aging chamber with a temperature of 80 °C and relative humidity (RH) of 85% for 30 days. Compared with the MXene film, the S-MXene film exhibited much improved oxidation resistance.



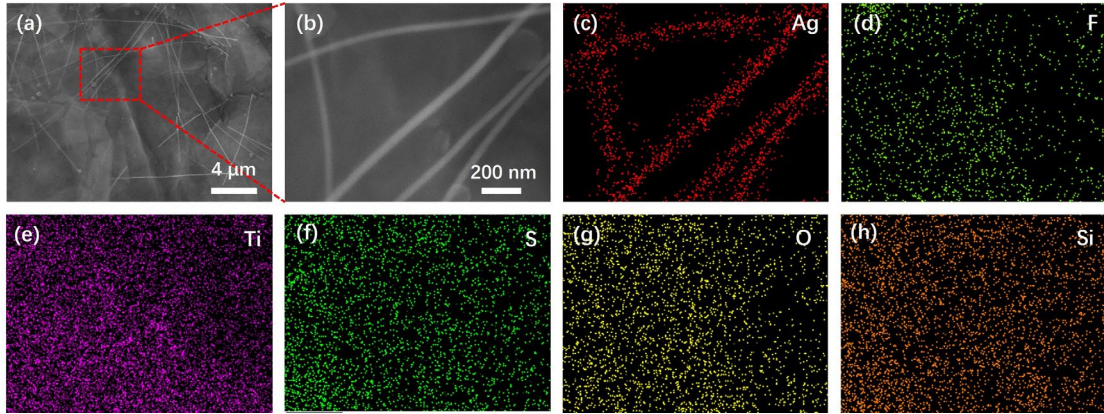
**Supplementary Fig. 4.** S-M/A sensing films with different thicknesses (T).



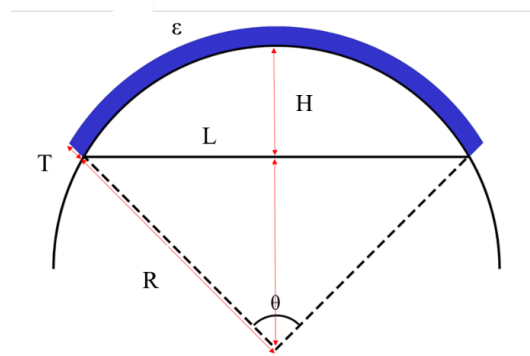
**Supplementary Fig. 5.** (a) Relative resistance variation as a function of large strain and its details for S-M/A<sub>1</sub> sensors with different thickness. (b) The calculated GF for the S-M/A<sub>1</sub> sensors with different thickness.



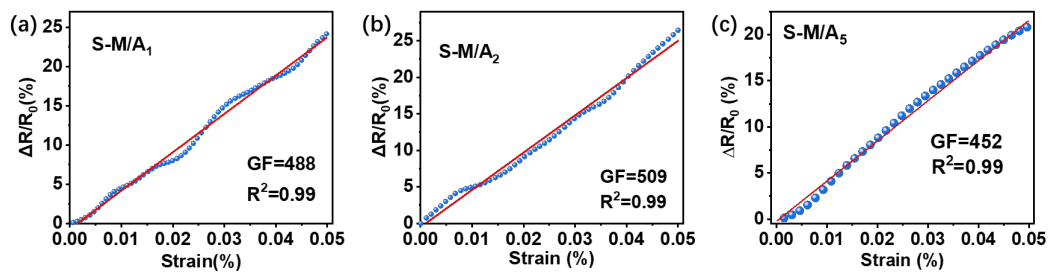
**Supplementary Fig. 6.** TEM images and corresponding EDS element maps of (a) and (b) AgNW and (c)-(h) S-MXene.



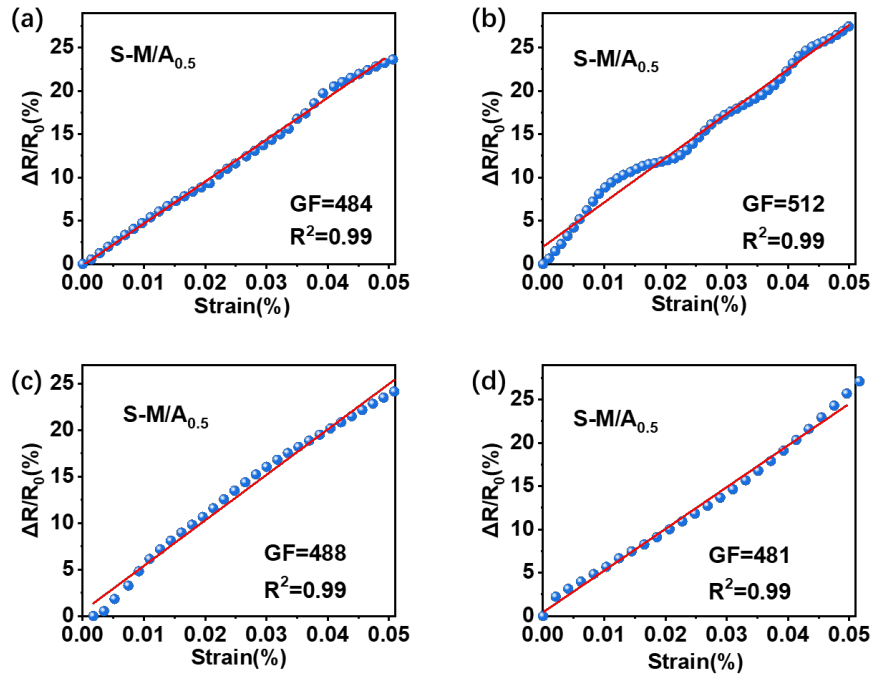
**Supplementary Fig. 7.** SEM images of original S-M/A film under 0% strain and corresponding elemental distribution.



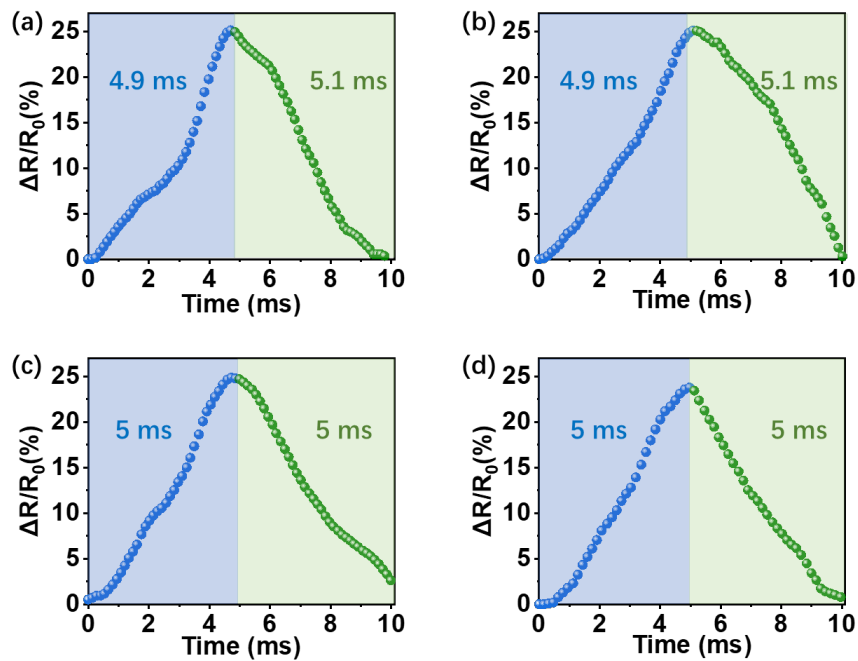
**Supplementary Fig. 8.** Calculation of the bending strain when bending the device to different strains,  $\varepsilon = T/2R$ , where  $T$  is the combined thickness of the sensing film and substrate, and  $R$  is the bending radius.



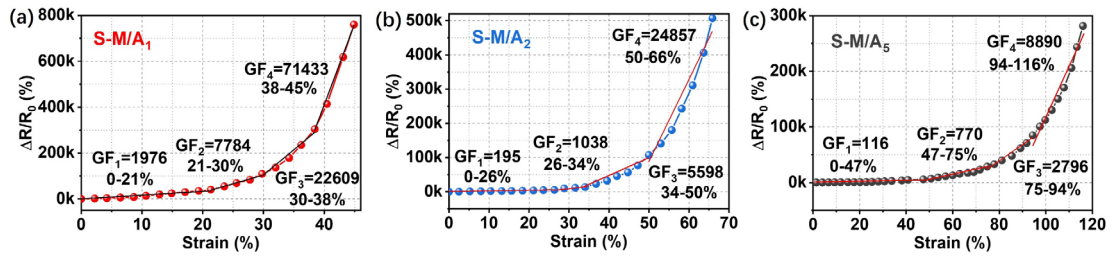
**Supplementary Fig. 9.** Relative resistance variation as a function of tiny strain (0–0.05%) for (a) S-M/A<sub>1</sub>, (b) S-M/A<sub>2</sub>, and (c) S-M/A<sub>5</sub> sensors.



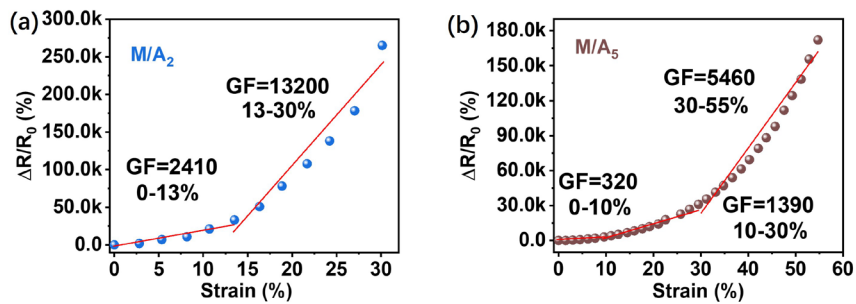
**Supplementary Fig. 10.** The other 4 repeated results of relative resistance variation as a function of tiny strain (0–0.05%) for the S-M/A<sub>0.5</sub> sensor.



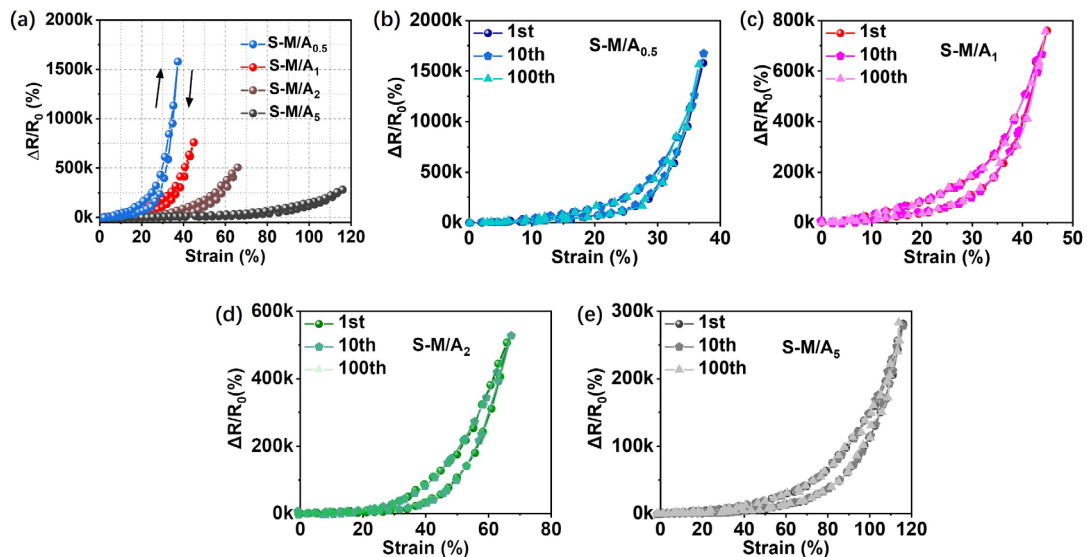
**Supplementary Fig. 11.** The other 4 repeated results of the transient sensing response and recovery time to an applied strain of 0.05% for the S-M/A<sub>0.5</sub> sensor.



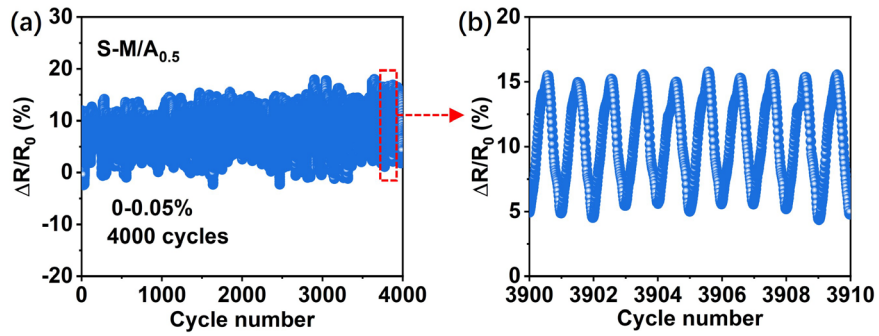
**Supplementary Fig. 12.** Relative resistance variation as a function of large strain for (a) S-M/A<sub>1</sub>, (b) S-M/A<sub>2</sub>, and (c) S-M/A<sub>5</sub> sensors.



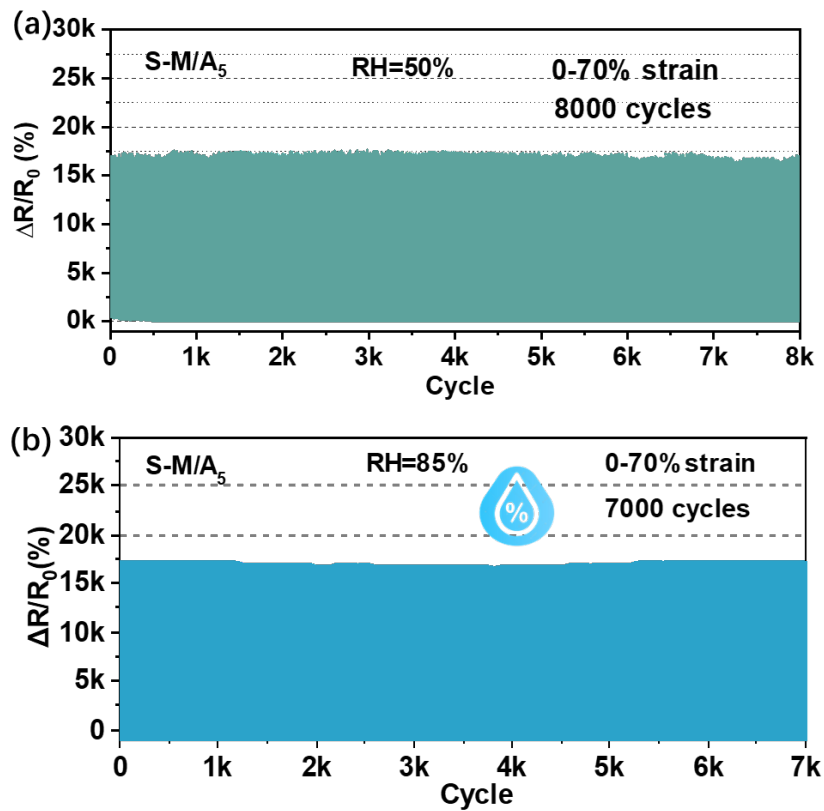
**Supplementary Fig. 13.** Relative resistance variation as a function of large strain for (a) M/A<sub>2</sub> and (b) M/A<sub>5</sub> sensors.



**Supplementary Fig. 14.** (a) Relative resistance variation as a function of large strain for S-M/A<sub>0.5</sub>, S-M/A<sub>1</sub>, S-M/A<sub>2</sub>, and S-M/A<sub>5</sub> sensors under one stretch-release cycle. Detailed relative resistance changes versus strain curves at 1st, 10th, and 100th stretch-release cycle for (b) S-M/A<sub>0.5</sub>, (c) S-M/A<sub>1</sub>, (d) S-M/A<sub>2</sub>, and (e) S-M/A<sub>5</sub> sensors.

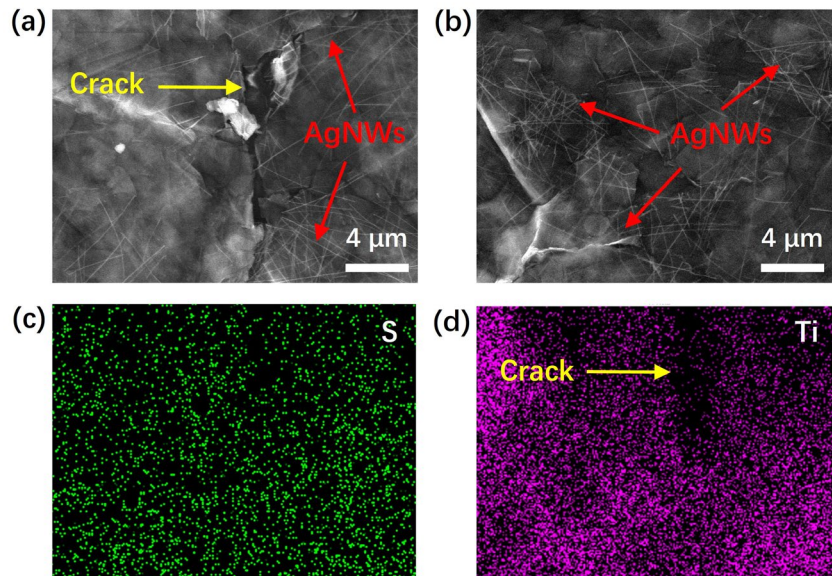


**Supplementary Fig. 15.** (a) Relative resistance changes of the S-M/A<sub>0.5</sub> sensor over 4000 stretch-release cycles in the strain range of 0–0.05%. (b) Detailed resistance changes recorded between 3900 and 3910 stretch-release cycles.

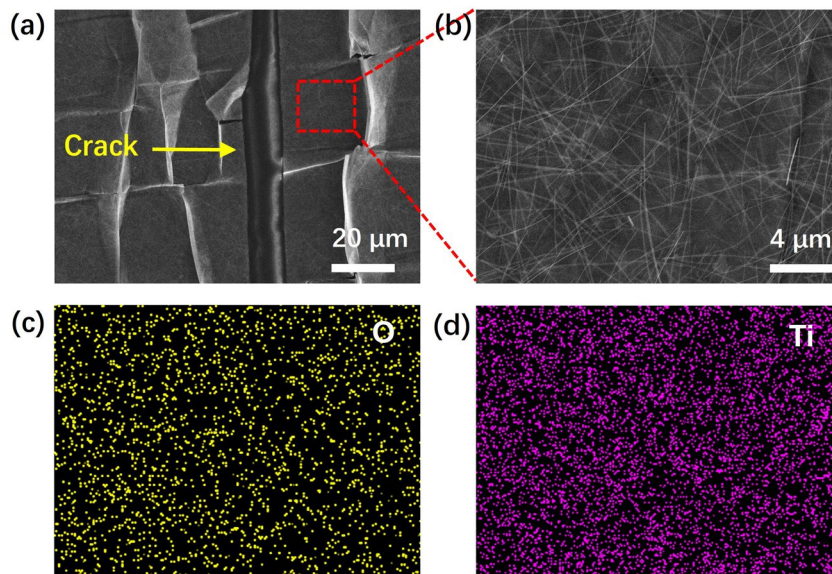


**Supplementary Fig. 16.** Relative resistance changes of S-M/A<sub>5</sub> sensor (a) over 8000 stretch-release cycles in the strain range of 0–70% under RH of 50% and (b) over 7000 stretch-release cycles in the strain range of 0–70% under RH of 85%.

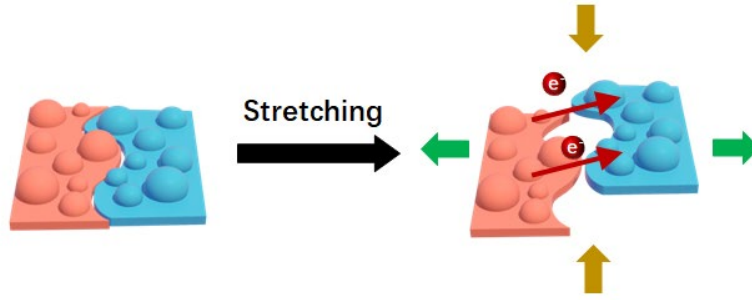




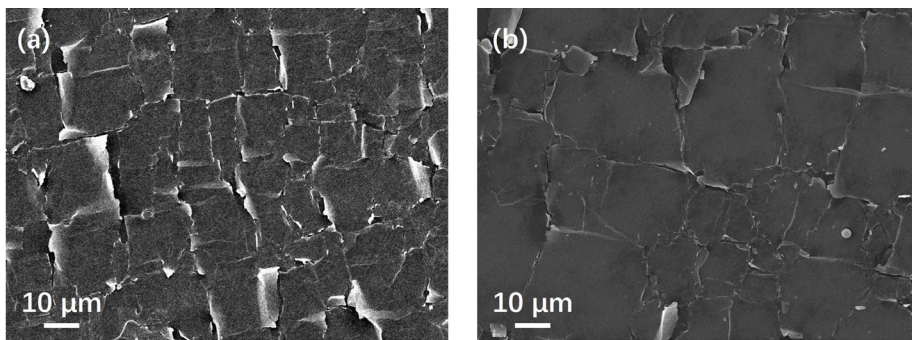
**Supplementary Fig. 17.** (a) and (b) Magnified SEM images of S-M/A film under 60% strain. EDS element maps of (c) S and (d) Ti from (a). Uniform distribution of AgNWs can be clearly seen in the S-M/A film.



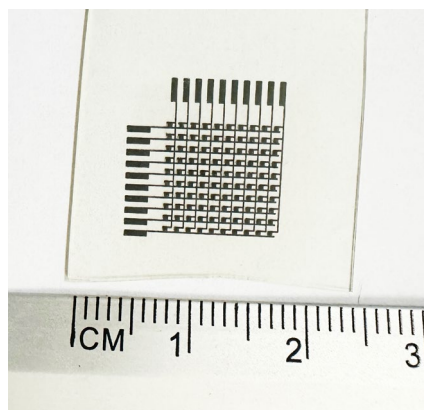
**Supplementary Fig. 18.** (a) and (b) SEM images of M/A film under 60% strain. EDS element maps of (c) O and (d) Ti from (b). Uniform distribution of AgNWs can be clearly seen in the M/A film.



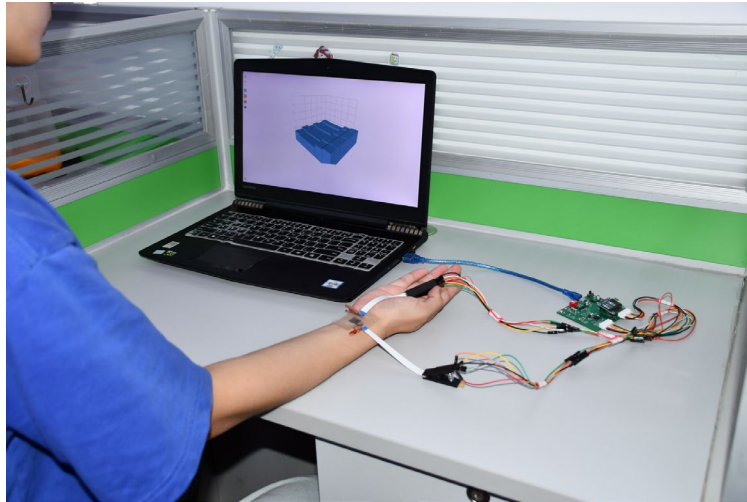
**Supplementary Fig. 19.** Schematic diagram of the proposed working principle of the tunneling effect for the crack-based S-M/A strain sensor.



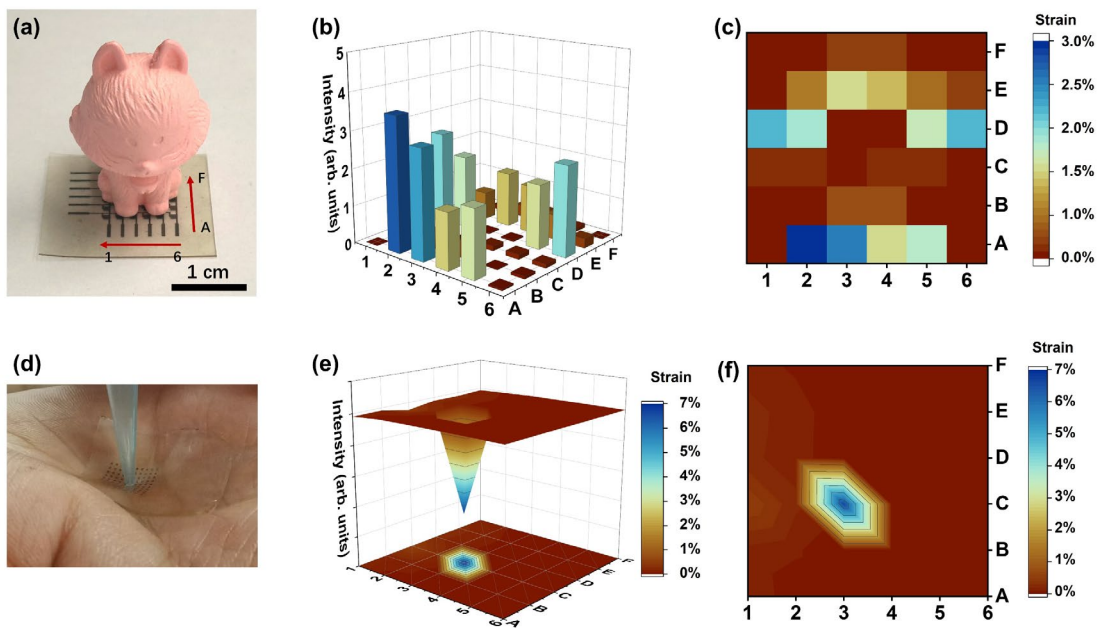
**Supplementary Fig. 20.** SEM images of S-M/A sensing film (a) under 100% strain and (b) after 5000 stretch-release cycles at 60% strain.



**Supplementary Fig. 21.** Photograph of a 100-channel S-M/A<sub>0.5</sub> strain sensor array with a device density of 100 sensors per square centimeter.

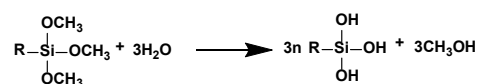


**Supplementary Fig. 22.** Photograph showing the monitoring of an artery pulse waveform of a volunteer using our multichannel pulse sensing system.

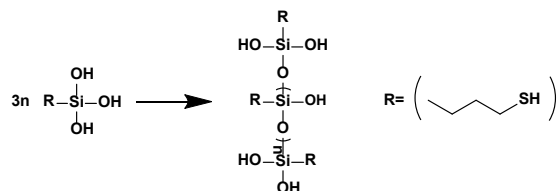


**Supplementary Fig. 23.** (a) Photograph of a 36-channel S-M/A<sub>1</sub> strain sensor array detecting a small object with complex shape, and (b) and (c) the corresponding intensity distribution of the normalized resistance change on the sensing array. (d) Photograph of a pipette tip poking on a 36-channel S-M/A<sub>1</sub> strain sensor array, and (e) and (f) the corresponding intensity distribution of the normalized resistance change on the sensing array.

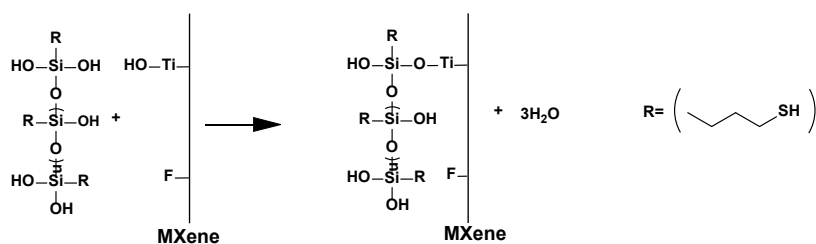
**Hydrolysis reaction:**



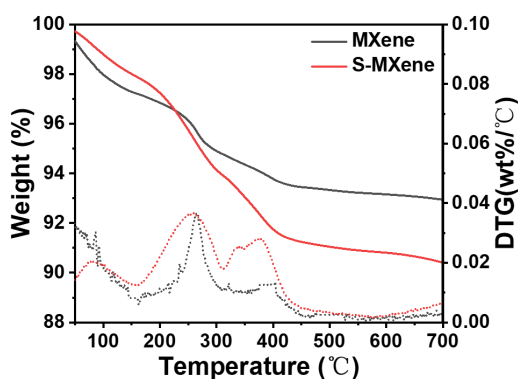
**Self-polymerization reaction:**



**Surface modification reaction:**



**Supplementary Fig. S24.** The hydrolysis, self-polymerization, surface modification reaction mechanism of MPTES.



**Supplementary Fig. S25.** TGA and DTG results for S-MXene and MXene. The content of MPTES grafted onto the S-MXene was about 3.6 wt%.

**Supplementary Table 1.**

Size (mm <sup>2</sup> )	Minimum detectable strain (%)	Maximum detectable strain (%)	Maximum Gauge factor	Response and Recovery time (ms)	Reference

0.25	0.001	37	152500	NA	This work
4	0.001	66	24900	NA	This work
25	0.001	116	8890	NA	This work
78.5	0.01	44	108241.7	NA	7
200	NA	100	12274	NA	8
75	0.000064	1	8699	0.107 @ 0.58 (0.1%)	9
56.25	NA	3	85000	NA	10
200	NA	145	42300	NA	11
50	NA	2	2000	NA	12
2000	0.1	170	1989	150 @ 150 (100%)	13
150	NA	100	363	NA	14
105	NA	2	16000	NA	15
30	NA	1	5000	NA	16
100	0.1	130	772.6	NA	17
120	0.025	74.1	1148.2	NA	18
60	NA	83	8700	NA	19
300	0.2	2	22.6	60 @ 60 (0.28%)	20
NA	0.006	0.8	450	NA	21
400	0.005	6.5	18000	258 @ 247 (0.65%)	22
224	0.5	0.9	1001	140 @ 228 (0.61%)	23
176.6	33	930	810	NA	24

**Supplementary Movie 1:** Real-time and dynamic display of the 3D pulse strength distribution measured by the 36-channel S-M/A<sub>1</sub> strain sensor array.

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